

*Cryogenic session: GWADW 19*

**Glasgow update: Thermal conductivity measurements of silicon and HCB and other relevant properties.**

LIGO-G1900974

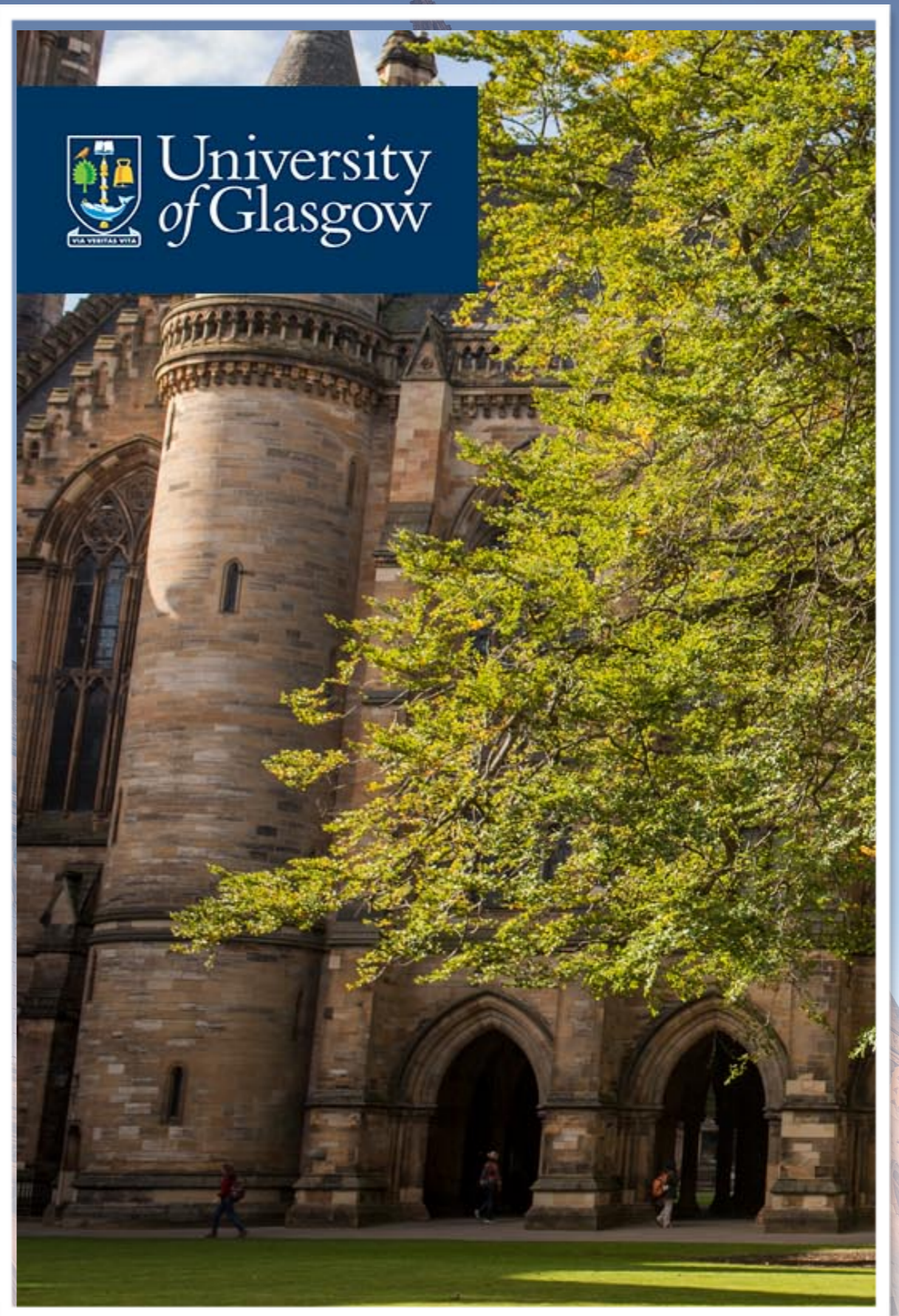
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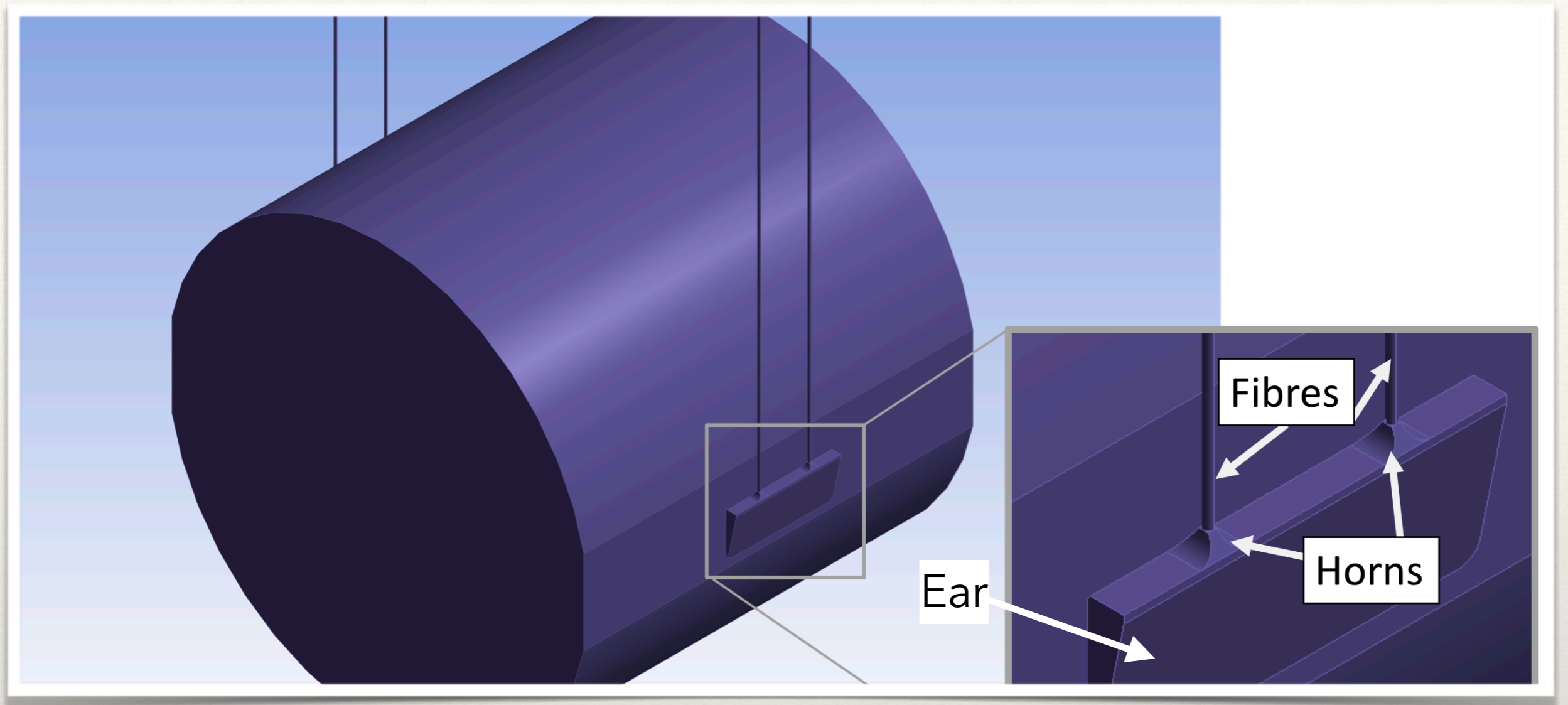


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# Content

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- ❖ Thermal conductivity of hydroxide catalysis bonds (HCB)
- ❖ Strength testing of HCB
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*3G-like suspension*

**The ears (to provide welding horns) are hydroxide catalysis bonded to the sides of the silica masses.**

ET-LF

Silicon

20 K

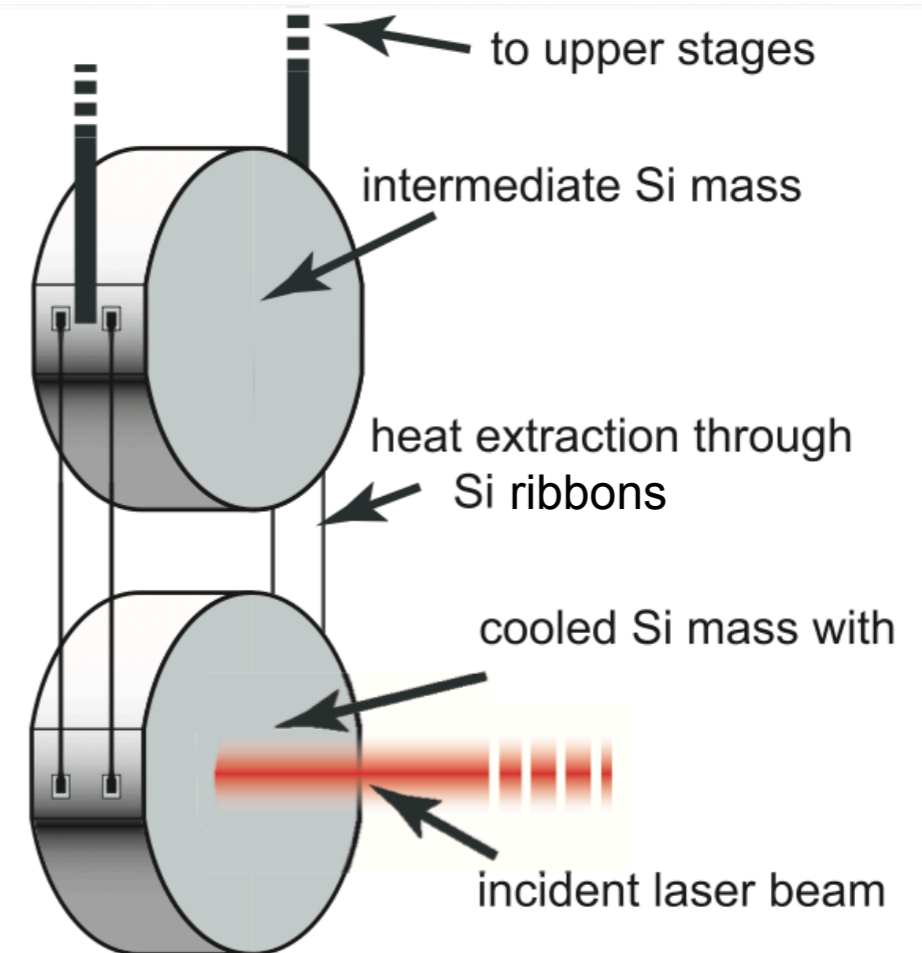
Silicon: Mechanical dissipation decreases with temperature, and linear coefficient of expansion goes to zero (and thus the thermoelastic thermal noise also goes to zero<sub>[1]</sub>) at ~120K and ~20K

{1} Rowan et al, Test mass materials for a new generation of gravitational wave detectors.2003

# Cryogenics

At cryogenic temperatures (below  $\sim 100\text{K}$ ) the heat is extracted from the mirror and through the suspension fibres. This includes heat extracted through the connection points and therefore through the silicate bonds.

lower stage suspension  
(quasi-monolithic silicon)



# Thermal conductivity

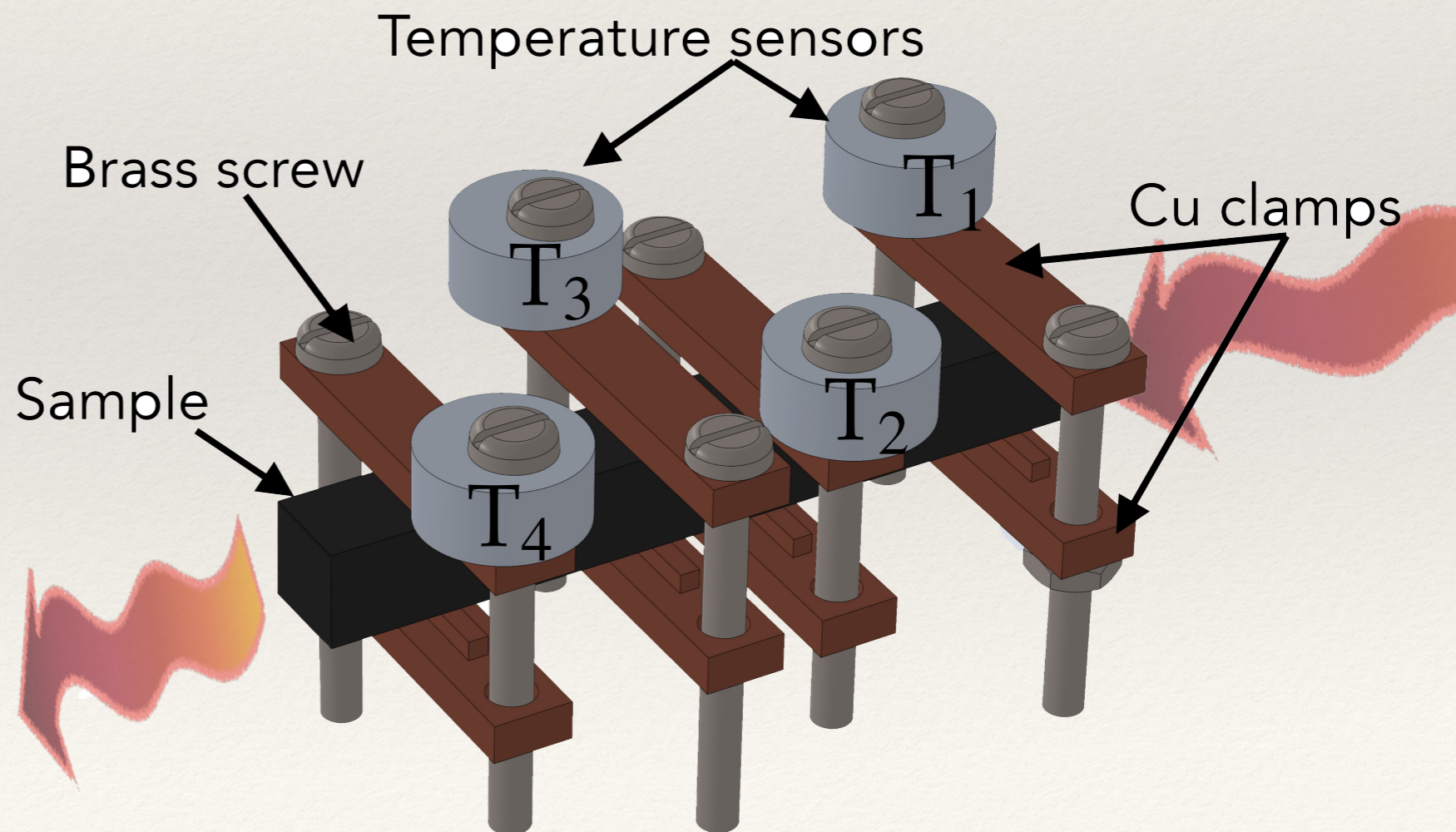
$P$  Power through the sample

$\Delta x$  Separation between sensors measuring the temperature

$A$  Cross sectional area of the sample

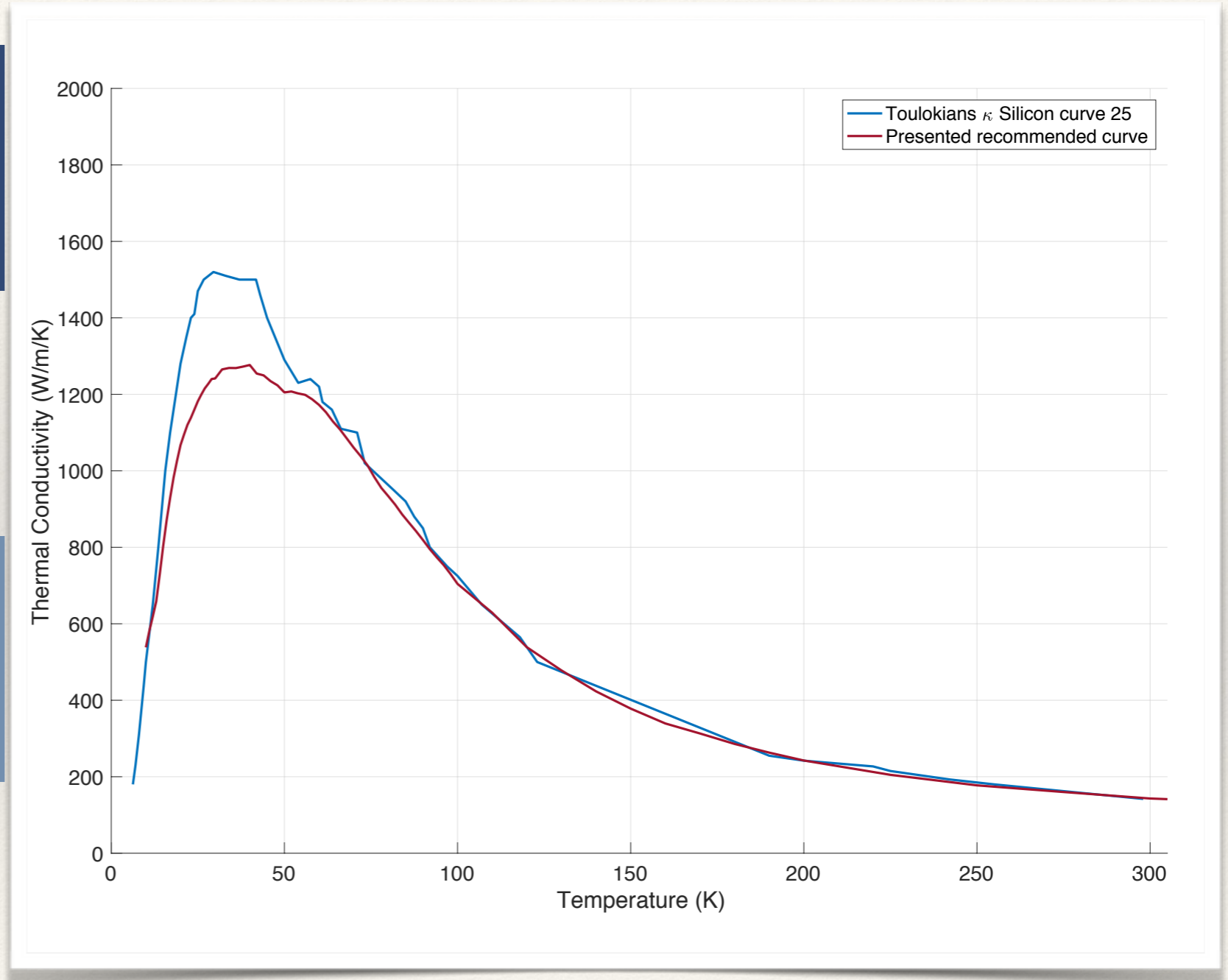
$\Delta T$  Temperature difference between the sensors

$$\kappa = \frac{P \Delta x}{A \Delta T}$$



# Thermal conductivity of silicon

Sample specs	Measured curve	Curve 25 (Touloukian)
O <sub>2</sub> cm <sup>3</sup>	$5.15 \times 10^{17}$	$7 \times 10^{17}$
Boron cm <sup>3</sup>	$6 \times 10^{15}$ < 0.01%	$4.8 \times 10^{15}$
R	2.32 Ω cm	3 Ω cm



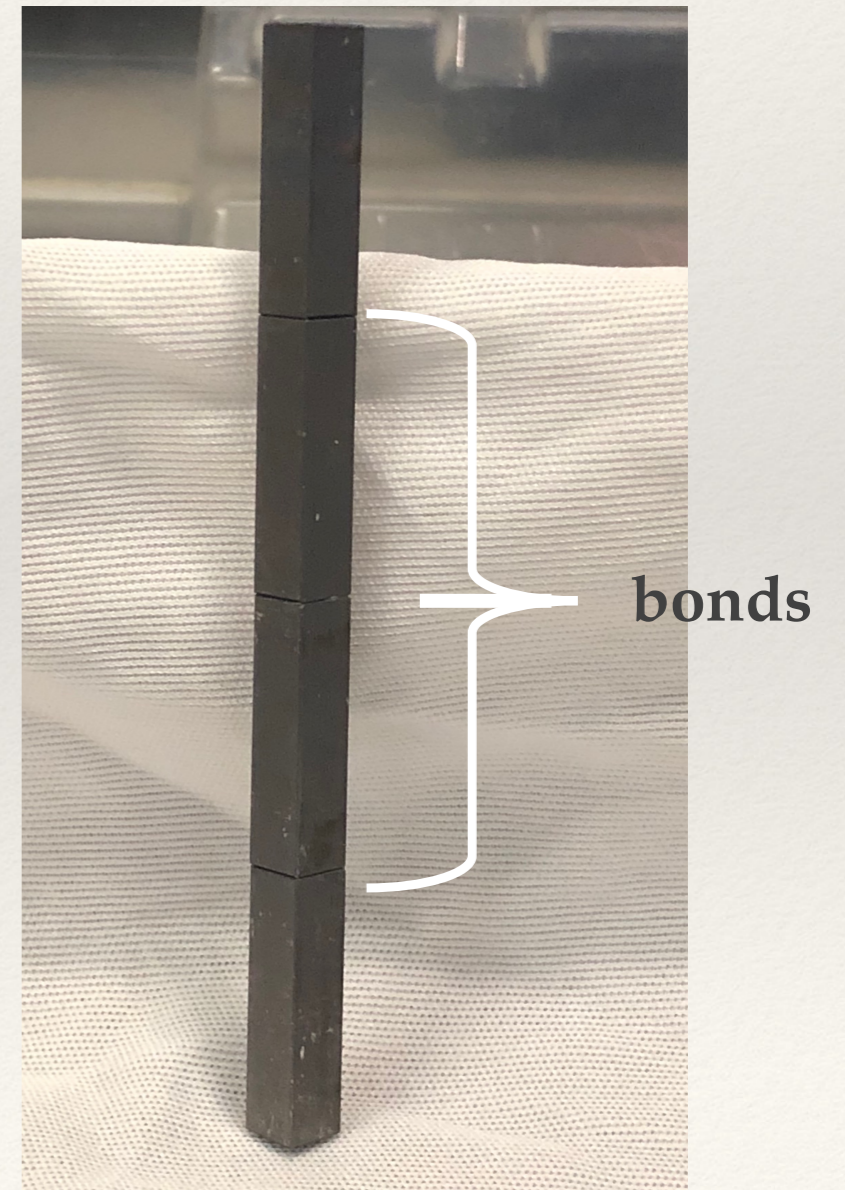
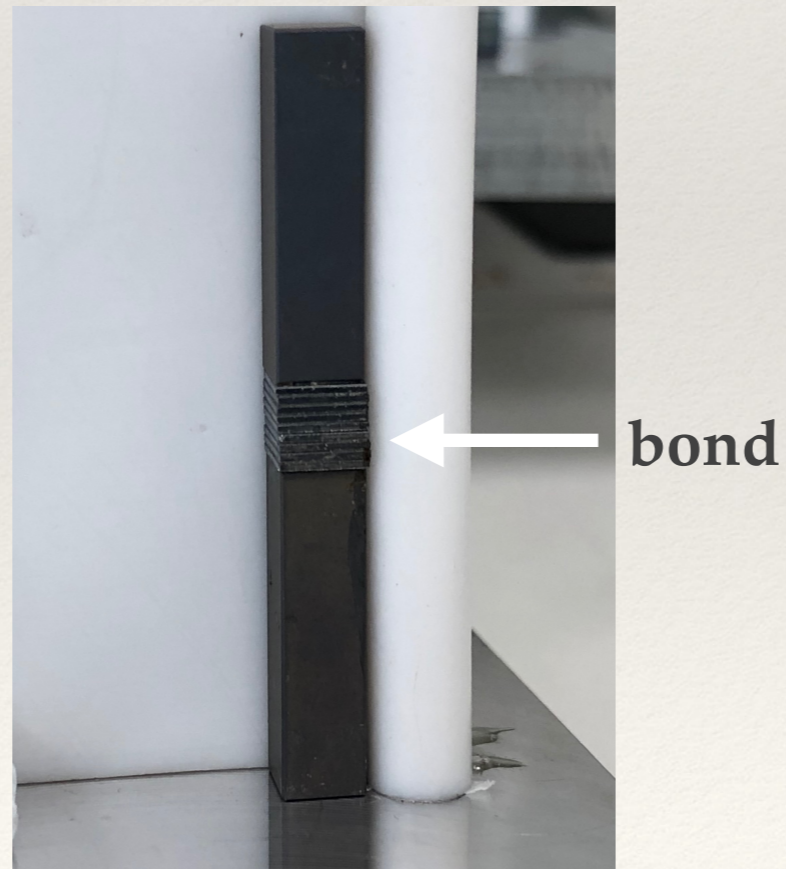
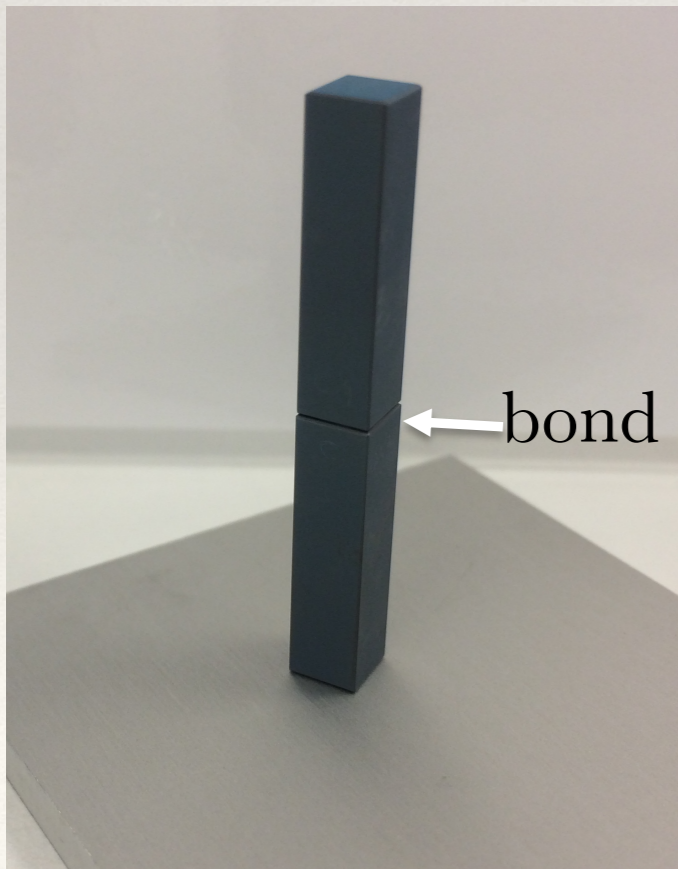
# Silicon bonded samples

5 x 5 x 20 mm silicon (100) bonded samples

*Single bond*

*10 bonds*

*3 bonds*



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# Extracting the thermal conductivity of the bond

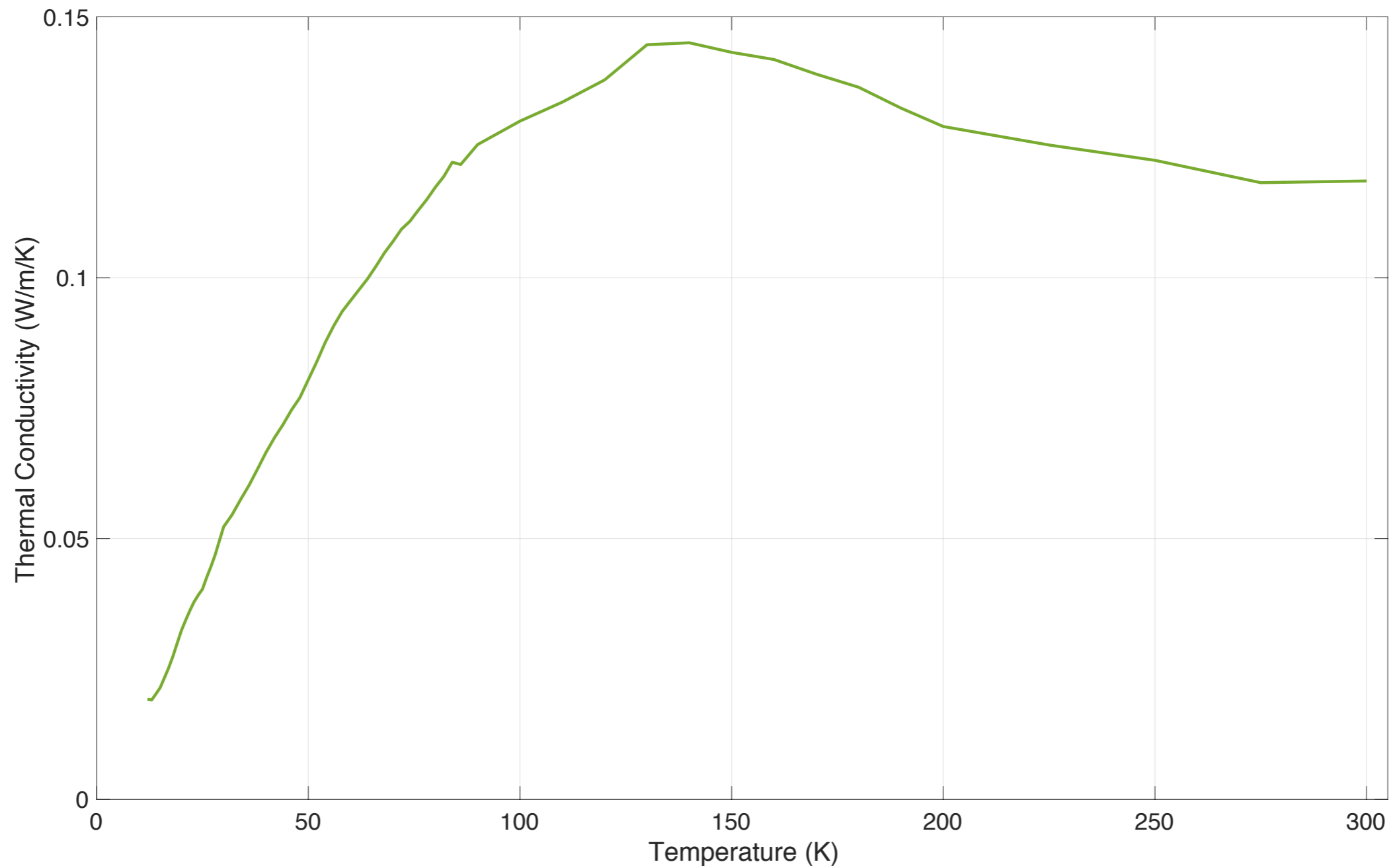
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$$\frac{L_{\text{total}}}{\kappa_{\text{total}} A_{\text{total}}} = \frac{L_{\text{bond}}}{\kappa_{\text{bond}} A_{\text{bond}}} + \frac{L_{\text{silicon}}}{\kappa_{\text{silicon}} A_{\text{silicon}}}$$

$$\kappa_{\text{bond}} = \frac{L_{\text{bond}}}{\frac{L_{\text{total}}}{\kappa_{\text{total}}} - \frac{L_{\text{silicon}}}{\kappa_{\text{silicon}}}}$$

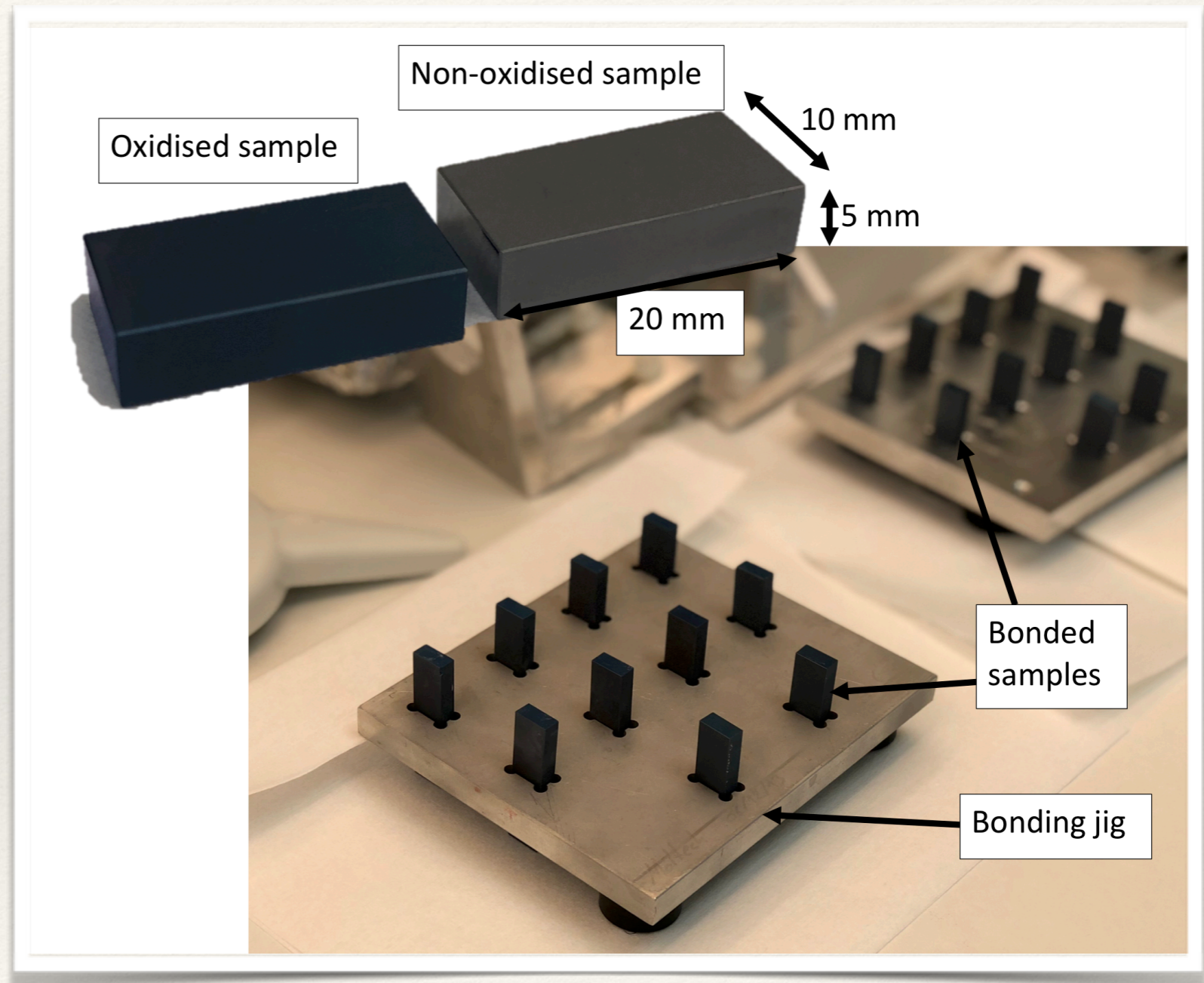


# Thermal conductivity of HCB



# Strength testing

- ❖ 40 samples where strength tested using a 4 point bend tester. 10 sets of the samples were tested at various curing times: 1 week, 2 weeks, 4 weeks and 26 weeks.



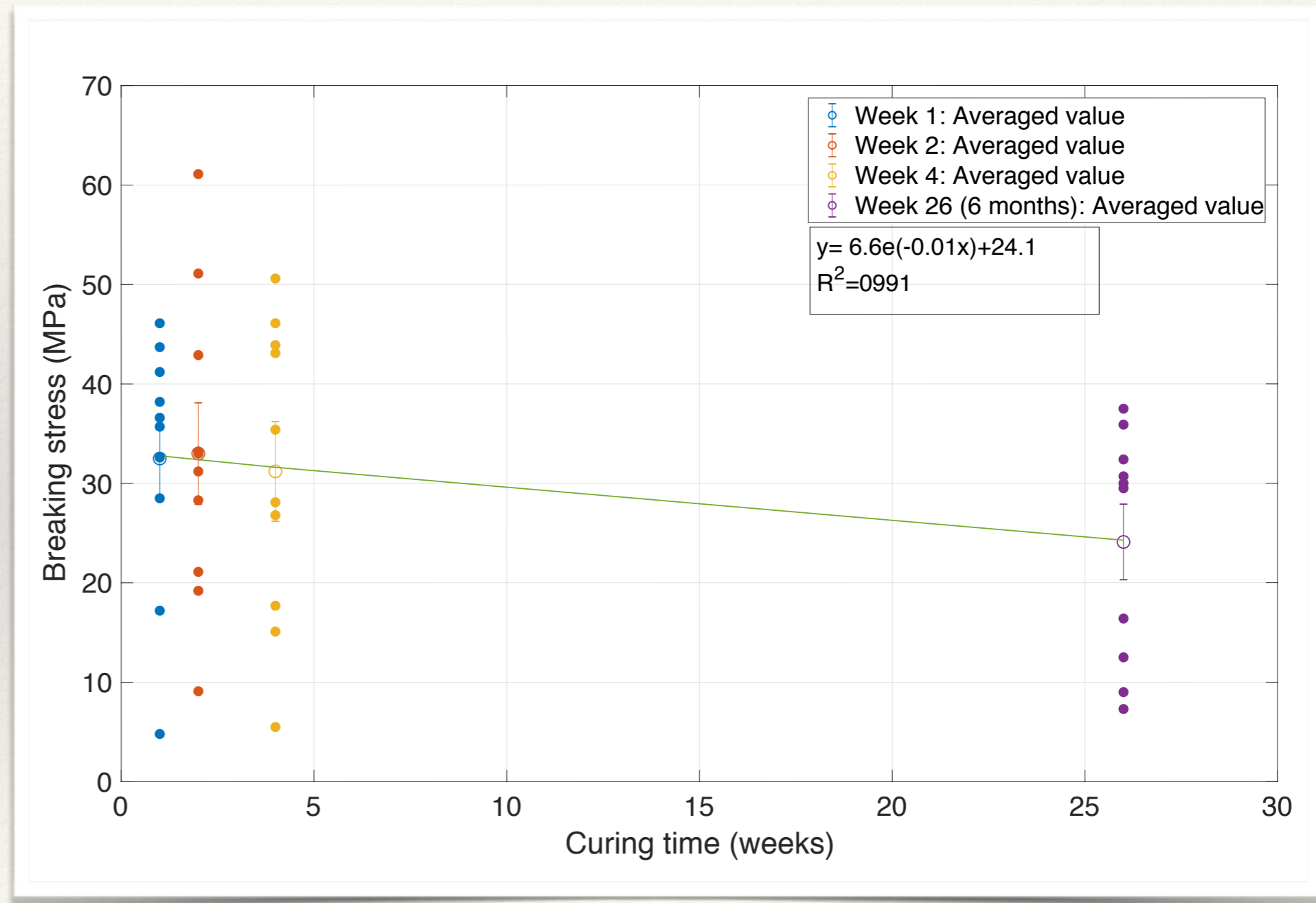
# Strength testing over time

## Breaking type

- ❖ Bond failure
- ❖ Bond break
- ❖ Diagonal break
- ❖ Oxide break

Weakest: 4.8 MPa.

Strongest: 61.1MPa.



# FEA analysis

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*Pressure profile simulates the probing laser beam proposed for ET-LF<sub>[3]</sub>*

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$$P = F_0 \frac{2}{\pi r^2} \exp\left(-2 \frac{x^2}{r^2}\right)$$

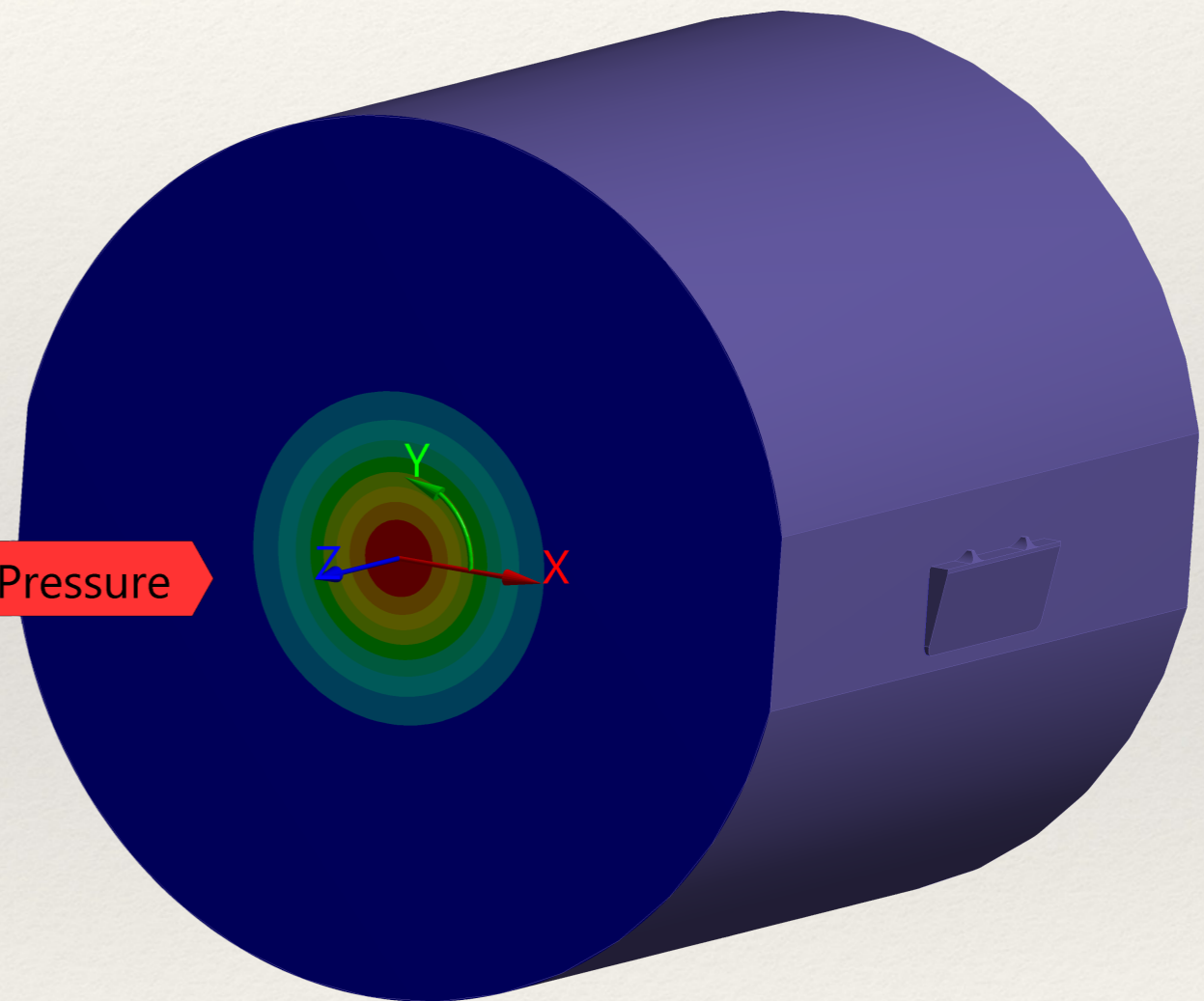
$P$  Gaussian pressure wave applied to the face of test mass.

$r$  Radius of beam (9 cm<sub>[3]</sub>).

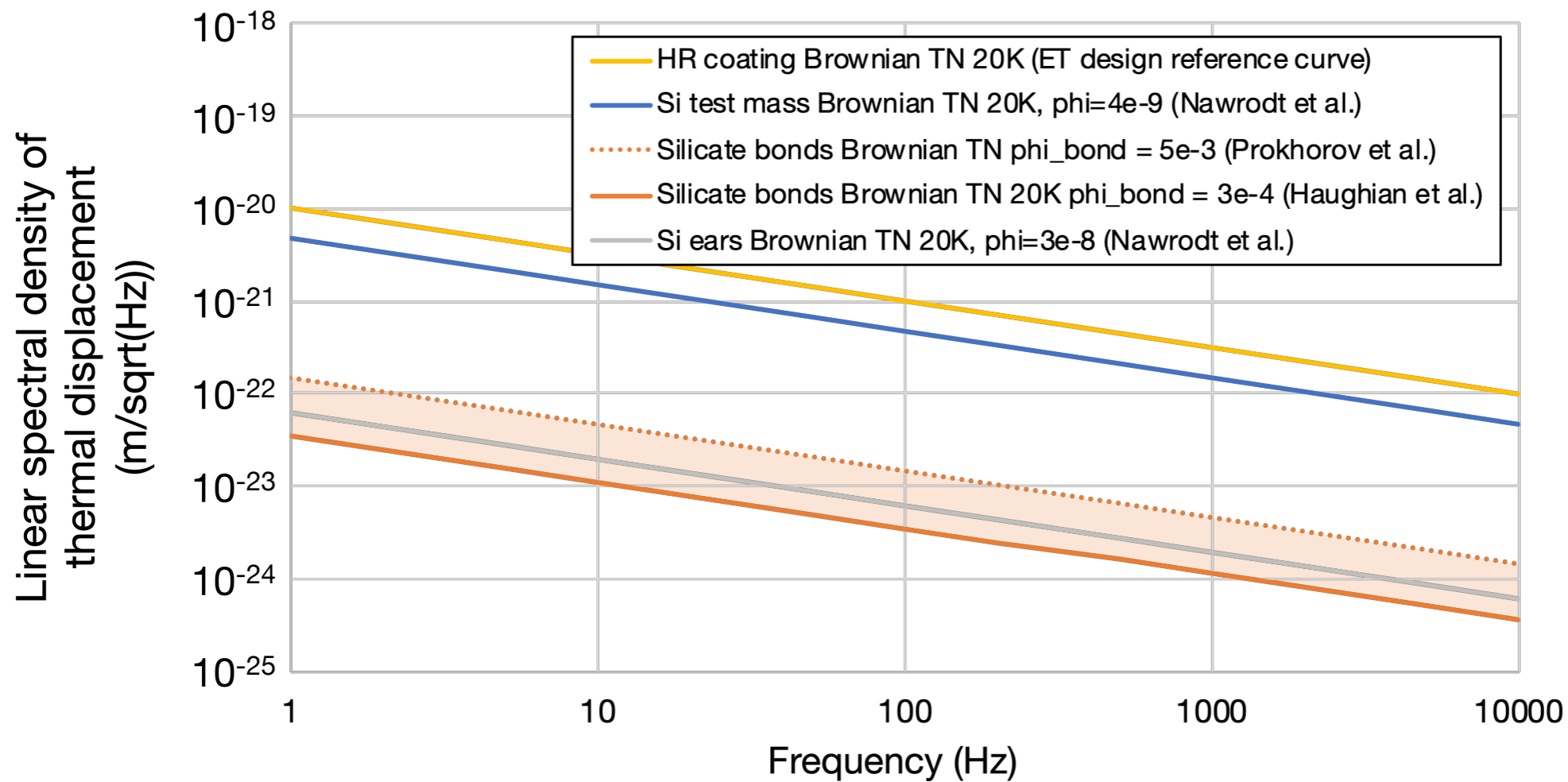
$x$  Distance from optical axis (orthogonal and central to the front face of test mass).

$F_0$  Constant force.

Variable Load: Pressure



# Thermal noise for an 3G-like suspension



Prokhorov measured TN of bonds between silicon substrates at  $\sim 120$  K.

Haughian measured TN of bonds between sapphire substrates at  $\sim 20$  K

*3G-like suspension at 20 K*

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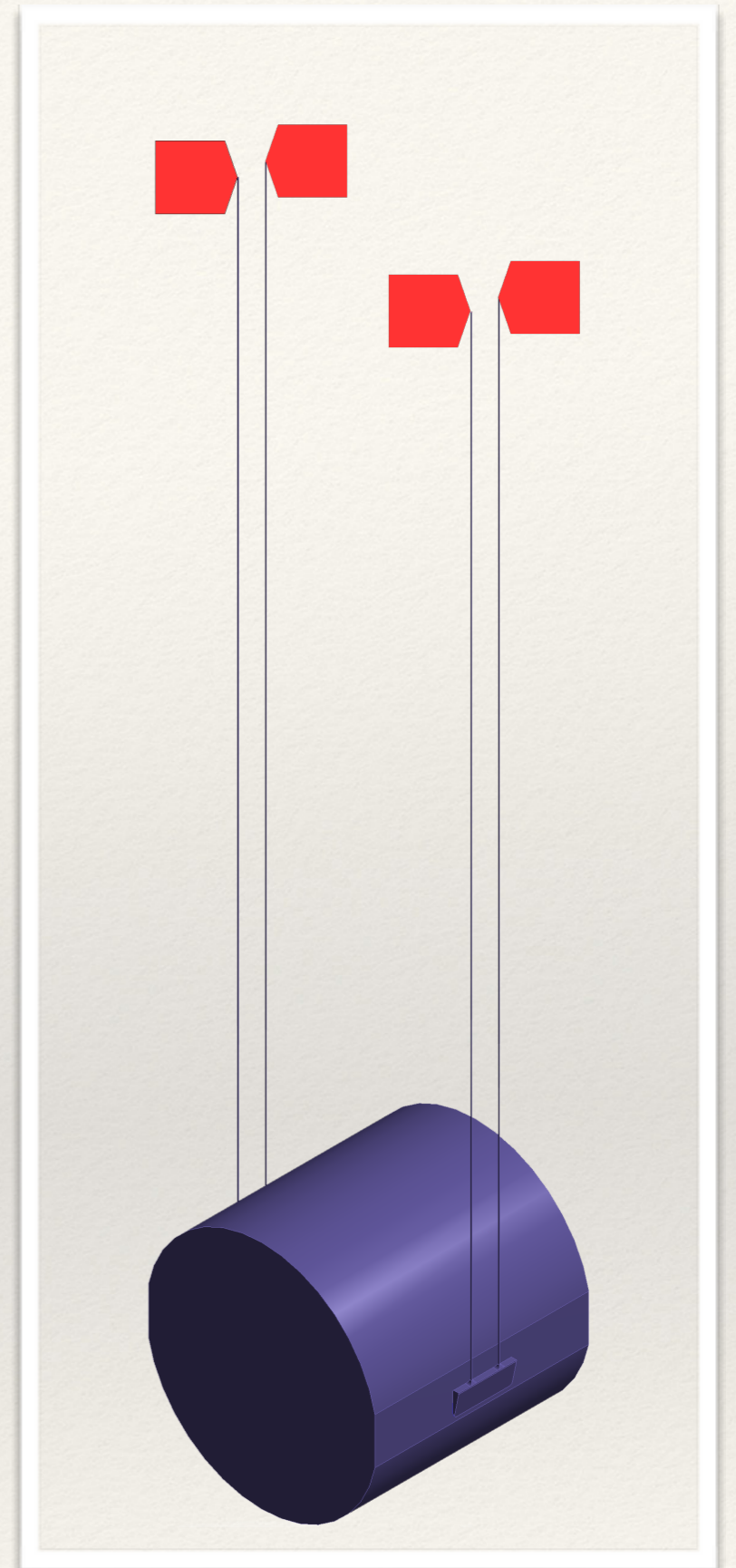
## FEA simulation for cool down of suspension

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Taking the ET-LF concept design, the heatsink temperature will be at 5 K and an operating temperature of  $\sim 20$  K. A fixed temperature of 5 K is applied at the top end of each fiber whilst the rest of the suspension is at 300 K.

Two models were taken into account:

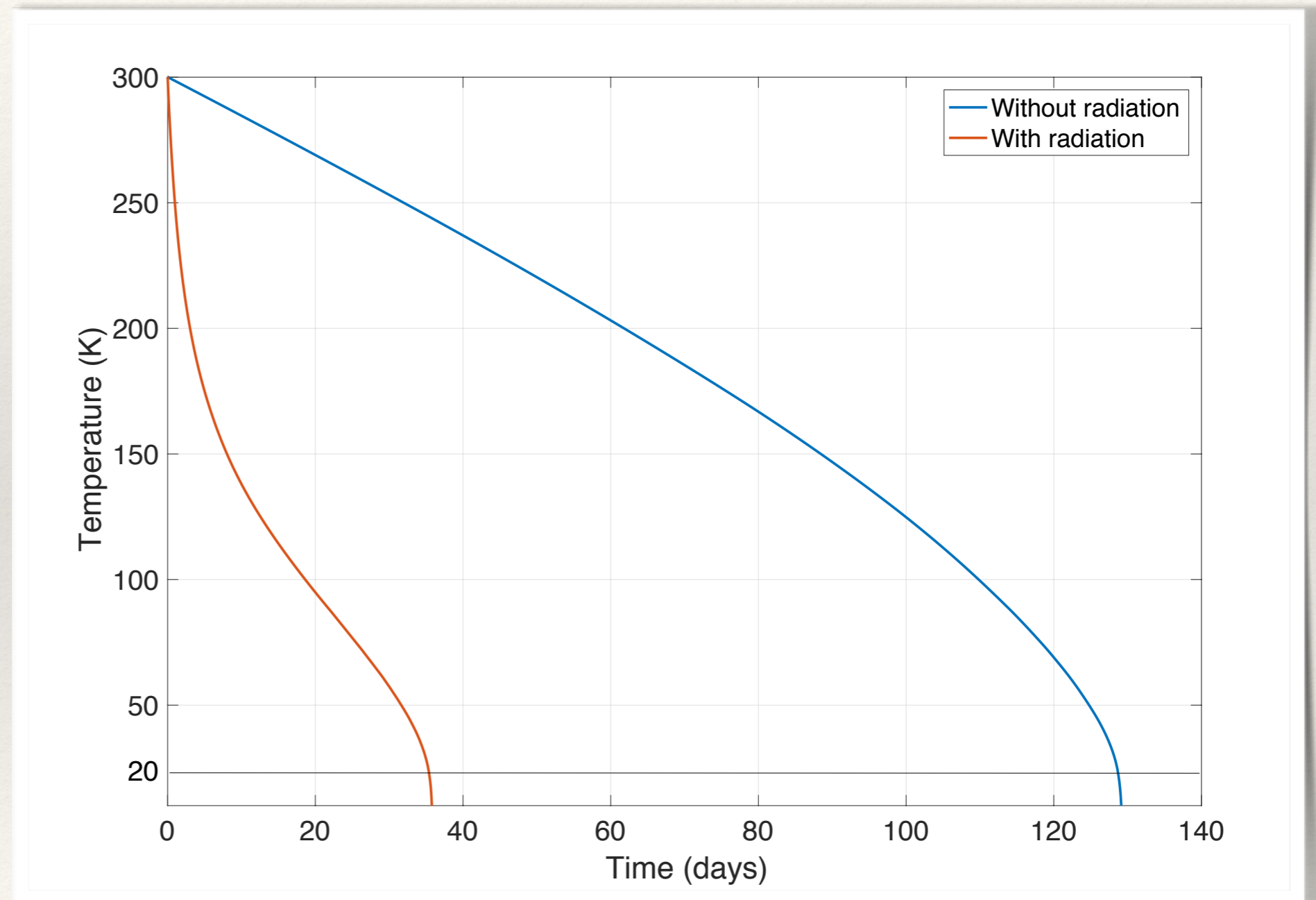
- ❖ Test mass cooled through conduction only (worst case scenario).
- ❖ Test mass cooled through conduction and radiation (surrounding at 5 K).



 Temperature: 5 K

# Cool-down rate for ET-LF silicon mirror suspension

- ❖ 3G-like final stage of suspension  
~35.5 days to reach 20 K.



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# Conclusions

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- ❖ Experimental measurements for the thermal conductivity of bonds between silicon substrates was conducted, showing a thermal conductivity at 20 K of 0.05 W / m / K.
- ❖ For an 3G-like configuration with a 15 K temperature difference between the mirror (20 K) and marionette (5 K)<sup>[3]</sup>, the additional temperature difference associated with the silicate bond is 14.5 $\mu$ K (assuming 1ppm absorption) or 262.2 $\mu$ K (assuming 20ppm absorption).
- ❖ Also for 120K test mass configuration, the thermal resistance of the bonds are negligible compare to that of the suspension elements (Voyager-like configuration gives  $\Delta T$  of 0.5mK across bonds).
- ❖ Based on the strength measurements presented, for the weakest value obtained (4.8 MPa), this would leave a safety margin of a factor of  $\sim 5$ , further validating the use of hydroxide catalysis bonding for the construction of future, quasi-monolithic, silicon mirror suspensions.
- ❖ An FEA simulation of the cool-down rate of an ET-LF mirror using a combination of conduction and radiation was calculated. It was found that a total of 35.5 days are required to reach the desired temperature.
- ❖ All details of the experimental measurements and simulations are described in my PhD thesis<sup>[5]</sup> (available online).

[3] *Einstein gravitational wave telescope conceptual design study*

[4] *Silicate Bonding Procedure (Hydroxide-Catalysis Bonding) LIGO-E050228-v4*

[5] Masso Herrera, Mariela C. (2019) *Properties of bonded silicon for future generations of gravitational wave observatories*. PhD thesis, University of Glasgow.